

Formation mechanism of ZrSiO₄ powders

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The formation mechanism of ZrSiO₄ powders from ZrO₂ and colloidal SiO₂ sols has been studied. The change in the ZrSiO₄ yield rate with seeding and non-seeding has also been investigated. The induction period of the ZrSiO₄ yield-rate curve corresponded to the $n = 1$ region, a simple nucleation region, on the Avrami plot. The $n = 1$ region was a rather wide range at 1200–1300 °C and the nucleation reaction was promoted in this temperature range. It was found that the ZrSiO₄ yield rate became high, even if seeding was not used, when the heating rate was controlled at less than 1 °C min⁻¹.

1. Introduction

Zircon (ZrSiO₄) is an oxide ceramic material known for its low thermal expansion coefficient [1]. ZrSiO₄ sintered bodies are used as refractories [2–4], developed for use under severe conditions, such as elevated temperatures. However, it is well known that the preparation of high-purity ZrSiO₄ powder is very difficult, because ZrSiO₄ is composed of only Si/Zr molar ratio = 1.0.

A few researchers have discussed the preparation of high-purity ZrSiO₄ powder. Komarneni and Roy [5] reviewed the synthesis process of ZrSiO₄, including the sol-gel and hydrothermal methods. Suzuki and Kanno [6–10] discussed the formation process by way of the sol-gel method. We have investigated the preparation method of high-purity ZrSiO₄ powders [11], and found that the ZrSiO₄ precursor with a Zr–O–Si bond was produced, and that single-phase ZrSiO₄ powder could be prepared using ZrOCl₂·8H₂O and SiO₂ sol.

In the present work, the preparation method of high-purity ZrSiO₄ powder without ZrSiO₄ precursor was examined and the formation mechanism of the powder is discussed here.

2. Experimental procedure

ZrO₂ sol (containing 20 wt % ZrO₂, Nissan Kagaku, Chiba, Japan) and colloidal SiO₂ sol (Snowtex-O, containing 20 wt % SiO₂, Nissan Kagaku, Chiba, Japan) were used as starting materials. The solution of each starting material was adjusted to pH = 5 with ammonia water as this was the optimum pH required to mix ZrO₂ and SiO₂ sols uniformly; the difference between ζ -potential of the ZrO₂ and SiO₂ solutions was greatest above that pH, the former being positive while the latter was negative.

These solutions were mixed in a separable flask for 24 h to produce an equimolar mixture solution. The

mixture was dried and 1 wt % commercial ZrSiO₄ (purified zircon sand, purity 98%, Kojundo Kagaku Kenkyusho, Saitama, Japan) was added as a seed and then ball-milled for 24 h with ethanol. The resultant slurry was subsequently dried in the evaporator to form the starting powder. It was heated to 700 °C at 20 °C min⁻¹ and then up to a given temperature (1200–1400 °C) at 0.15–10 °C min⁻¹, at which it was held for 20 min. The yield for the calcined ZrSiO₄ powders was determined using X-ray diffractometry. The four peaks appearing at a diffraction angle 2θ in the range 26°–32° in the X-ray diffraction patterns related to ZrSiO₄(200), m-ZrO₂(111, 11-1), t-ZrO₂(101) planes, were used as standards to determine the relative intensity from each peak, and then the yield, α_{ZrSiO_4} , was calculated using the equation

$$\alpha_{\text{ZrSiO}_4} = I_{\text{ZR}(200)} / [I_{\text{ZR}(200)} + I_{\text{M}(111)} + I_{\text{M}(11-1)} + I_{\text{T}(101)}] \quad (1)$$

where subscripts ZR, M and T stand for ZrSiO₄, m-ZrO₂ and t-ZrO₂, respectively. The numbers in parentheses indicate the plane index.

3. Results and discussion

Fig. 1 shows relation between holding time and ZrSiO₄ yield rate, α_{ZrSiO_4} , at 1300 °C, at the heating rate of 1.25 °C min⁻¹, with and without seeding. The ZrSiO₄ yield increased with increasing holding time in each case. Vilmin *et al.* [12] reported that ZrSiO₄ preparation was affected by seeding. Therefore, in order to research the formation mechanism of ZrSiO₄, the nucleation behaviour was investigated with and without seeding. Fig. 2 shows the relation between holding time and ZrSiO₄ yield rate at 1200–1400 °C without seeding, at a heating rate of 1.25 °C min⁻¹. The ZrSiO₄ yield rate increased with increasing hold-

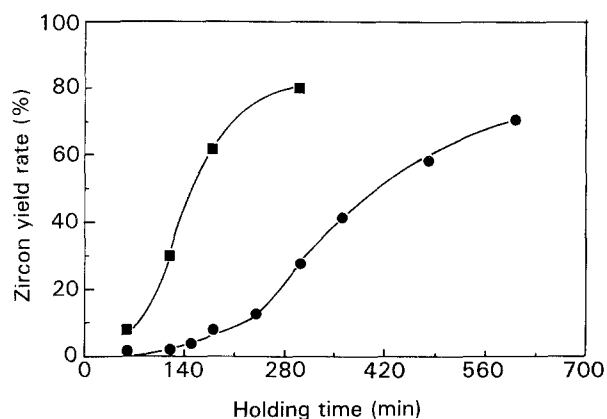


Figure 1 Zircon yield rate as a function of holding time. Calcination temperature 1300°C, heating rate 1.25°C min⁻¹. (■) 1.5 wt% seeding, (●) unseeded.

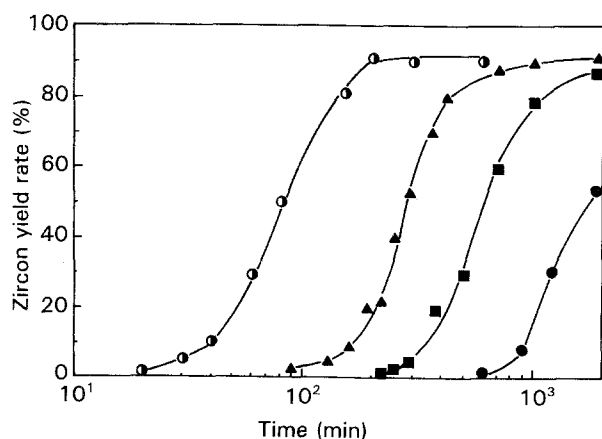


Figure 2 Zircon yield rate as a function of time, without seeding. Heating rate 1.25°C min⁻¹. (●) 1200°C, (■) 1250°C, (▲) 1300°C, (○) 1400°C.

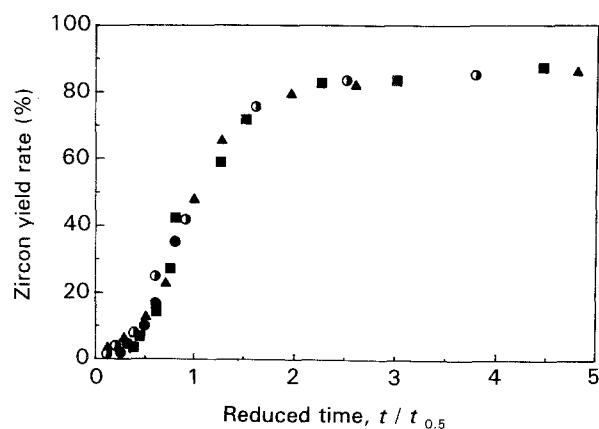


Figure 3 Zircon yield rate as a function of reduced time, without seeding. (●) 1200°C, (■) 1250°C, (▲) 1300°C, (○) 1400°C.

ing time, and the ZrSiO₄ yield-rate curve was observed to be "S"-shaped.

Fig. 3 shows the relation between the ZrSiO₄ yield rate and the reduced time, $t/t_{0.5}$, based on the results of Fig. 2, where the $t_{0.5}$ is the half the time at which the ZrSiO₄ yield rate was saturated and t is the holding time. If the ZrSiO₄ yield as a function of reduced time, $t/t_{0.5}$, fitted a curve in some temperature region, the reaction mechanism was the same in that temperature range. In Fig. 3, the results fitted a single curve at these

temperatures, and consequently the reaction mechanism was the same.

Fig. 4 shows the result of an Avrami plot obtained from the data of Fig. 2. The line of the Avrami plot comprised two slopes; one with $n = 1$ and the other with $n \geq 2$. On the basis of the results of Fig. 4, the $n = 1$ region was determined. Table I shows the $n = 1$ region using the Avrami plot on Fig. 4 and the induction period of the ZrSiO₄ yield-rate curve at each calcination temperature, the initial region of "S"-shaped curve. The $n = 1$ region is a region of a simple nucleation reaction without nucleus growth corresponding to the induction time of the ZrSiO₄ yield-rate curve on Fig. 2. The $n = 2-3$ region means the mixed region of nucleation and nucleus growth. Therefore, the simple nucleation region has a wide range from 1200–1300°C.

Thus, in order to compare the results with the unseeded case, the effect of seeding was investigated. Fig. 5 shows the relation between holding time and ZrSiO₄ yield rate with 1.5 wt% seeding in the same manner as Fig. 2. The ZrSiO₄ yield-rate curve was again "S"-shaped. The tendency of these results was similar to that in Fig. 3. Fig. 6 shows the results of an Avrami plot using data of Fig. 5. On the basis of the results of Fig. 6, the $n = 1$ region was determined. Table II shows the induction time in Fig. 5 and the time to reach the $n = 1$ region in Fig. 6 at 1200, 1250 and 1300°C. The tendency was similar to Table I and these data corresponded to each other.

The $n = 1$ region decreased rapidly with increasing temperature. Thus, in order to enhance the effect of nucleation, the heating rate was varied from 0.15–10°C min⁻¹ and then the ZrSiO₄ yield rate was

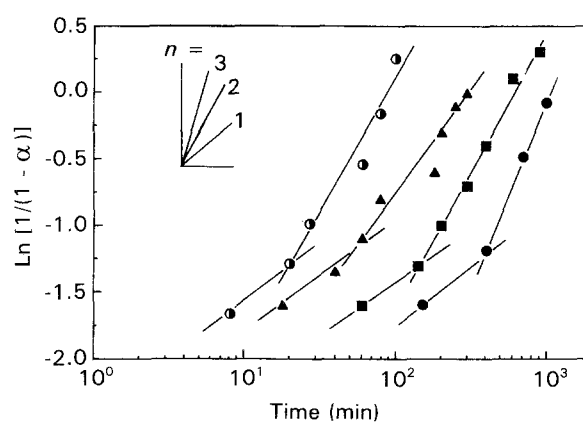


Figure 4 $\ln [1/(1 - \alpha)]$ as a function of time, without seeding. Heating rate 1.25°C min⁻¹. (●) 1200°C, (■) 1250°C, (▲) 1300°C, (○) 1400°C.

TABLE I Time at the $n = 1$ region and the induction time without seeding at various temperatures

Calcination temperature (°C)	Time at $n = 1$ region (min)	Induction time (min)
1200	250	400
1250	90	80
1300	40	50
1400	12	20

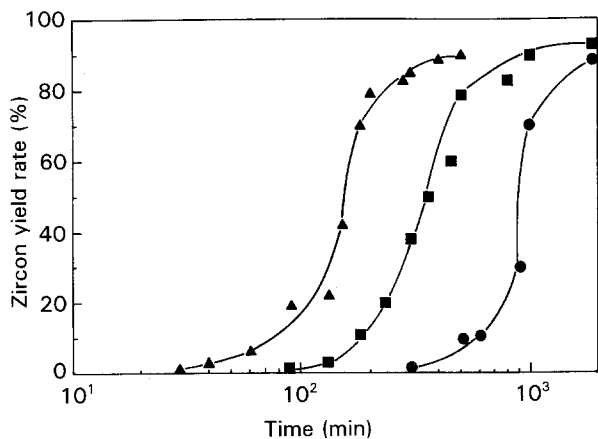


Figure 5 Zircon yield rate as a function of time with 1.5 wt % seeding. Heating rate $1.25^{\circ}\text{C min}^{-1}$. (●) 1200°C , (■) 1250°C , (▲) 1300°C .

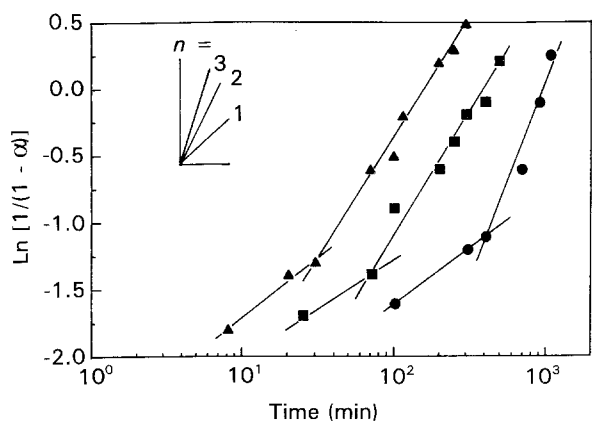


Figure 6 $\text{Ln}[1/(1-\alpha)]$ as a function of time with 1.5 wt % seeding. Heating rate $1.25^{\circ}\text{C min}^{-1}$. (●) 1200°C , (■) 1250°C , (▲) 1300°C .

TABLE II Time at the $n = 1$ region and the induction time with 1.5 wt % seeding at various temperatures

Calcination temperature ($^{\circ}\text{C}$)	Time at $n = 1$ region (min)	Induction time (min)
1200	300	300
1250	45	50
1300	22	30

investigated. Fig. 7a shows the relation between heating rate and ZrSiO_4 yield rate with the addition of 1.5 wt % ZrSiO_4 seed, and Fig. 7b shows the relation between the heating rate and ZrSiO_4 yield rate without seeding. From Fig. 7a, a remarkable effect of heating rate appeared at $1200\text{--}1250^{\circ}\text{C}$, but there was virtually no effect above 1300°C . From Fig. 7b, the effect of heating rate is seen to be similar to that of Fig. 7a, but the zircon yield rate depended on heating rate and the slope of the curve was greater than that in Fig. 7a. The ZrSiO_4 yield rate was more than 80%, even if the calcination temperature was 1300°C or less and seeding was not used, when the heating rate was

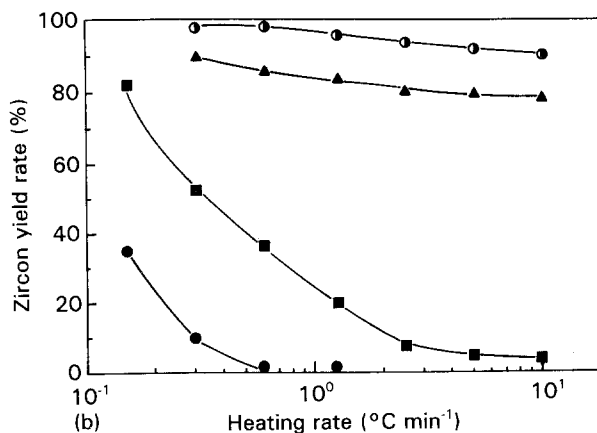
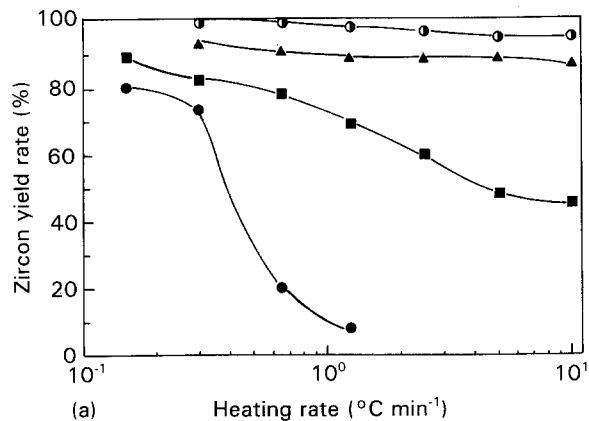


Figure 7 Zircon yield rate as a function of heating rate (a) with 1.5 wt % seeding, and (b) without seeding. Holding time 20 min. (●) 1200°C , (■) 1250°C , (▲) 1300°C , (○) 1400°C .

$0.15^{\circ}\text{C min}^{-1}$. From Fig. 7a and b, the difference between seeding and non-seeding is seen to be slight at $1350\text{--}1400^{\circ}\text{C}$. As mentioned above, the nucleation increased when the heating rate was slow at $1200\text{--}1300^{\circ}\text{C}$, where the $n = 1$ region was wide, and the effect of seeding was remarkable in this case. However, the effect of seeding was only slight at $1350\text{--}1400^{\circ}\text{C}$ where the $n = 1$ region was narrow. Therefore, it was found that the ZrSiO_4 yield rate increased remarkably at $1200\text{--}1300^{\circ}\text{C}$ without seeding when the heating rate was less than $1^{\circ}\text{C min}^{-1}$. Moreover, the value reached more than 80% at a relatively low temperature (1250°C).

4. Conclusions

The formation mechanism of ZrSiO_4 and the preparation of ZrSiO_4 powder from ZrO_2 and colloidal SiO_2 sols was investigated. The following conclusions were drawn from the results.

1. The relation between the holding time and ZrSiO_4 yield rate, α_{ZrSiO_4} , showed an "S"-shaped curve with and without seeding. In order to consider the preparation mechanism of ZrSiO_4 , the Avrami plot was drawn using seeded and unseeded data. The induction time of the ZrSiO_4 preparation reaction corresponded to the $n = 1$ region, a simple nucleation region.

2. The $n = 1$ region decreased rapidly with increasing temperature, but it was present over a wide range

at 1200–1300 °C and the nucleation reaction was promoted at these temperatures.

3. The seeding effect disappeared above 1300 °C, because the $n = 1$ region became very narrow above 1300 °C.

4. In the formation reaction of $ZrSiO_4$, the predominant factor affecting this was the nucleation reaction. In particular, the temperature range from 1200–1300 °C, in which the $n = 1$ region of the Avrami plot showed a wide range, was important. It was found that the $ZrSiO_4$ yield rate became very high, even if no seeds were added, when the heating rate was controlled at less than $1\text{ }^\circ\text{C min}^{-1}$.

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